



## LIST OF REFERENCES CITED BY APPLICANT

(Use several sheets if necessary)

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Applicant No.

10/076.296

Applicant

Conant et al.

Filing Date

February 13, 2002

Serial #

To be assigned

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE APPROPRIATE
✓	AA	6,201,629	3/13/01	McClelland et al.			
✓	AB	5,959,760	9/28/99	Yamada et al.			

## FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
✓	AC	PCT/US01/15514	5/14/01	PCT Int'l Search Report			

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

✓	AD	Kam Y. Lau, "Microscanner Raster-scanning Display: A Spyglass for the Future", Optics & Photonic News, May 1999 Vol. 10 No. 5, pages 47-50, 84					
	AE	Nee et al. "Stretched-Film Micromirrors For Improved Optical Flatness", IEEE MEMS 2000 Conference, January 23-27, 2000, Miyazaki, Japan					
	AF	Conant et al. "Robustness and Reliability of Micromachined Scanning Mirrors", MOEMS 1999, Mainz Germany, August 1999					
	AG	Hagelin et al. "Integrated Micromachined Scanning Display Systems", presented at 18 <sup>th</sup> Congress of the International Commission for Optics, San Francisco, CA, August 1999					
	AH	Conant et al. "A Raster-Scanning Full-Motion Video Display Using Polysilicon Micromachined Mirrors", proc. Transducers '99, Sendai, Japan, June 1999, pp. 376-379					
	AI	Hart et al. "Time-Resolved Measurement of Optical Memes Using Stroboscopic Interferometry", proc. Transducers '99, Sendai, Japan, June 1999, pp. 470-473					
	AJ	Nee et al. "Scanning Blazed-Grating for High-Resolution Spectroscopy", 1998 Workshop for Solid State Sensors and Actuators (HH '98) Late News Poster Session Supplemental Digest, Hilton Head Island, June 8-11, 1998, pgs. 9-10					
	AK	Kiang et al. "Surface-Micromachined Diffraction Gratings for Scanning Spectroscopic Application", proc. Transducers '99, Sendai, Japan, June 1999, pp. 998-1001					
	AL	Nee et al. "Lightweight, Optically Flat Micromirrors for Fast Beam Steering", IEEE/LEOS Optical MEMS 2000, Kauai, Hawaii, August 21-24, 2000					
✓	AM	Conant et al. "A Flat High-Frequency Scanning Micromirror", 2000 Workshop for Solid State Sensors and Actuators (HH2000), Hilton Head Island, SC, USA, June 4-8, 2000, pp. 6-9, Digest of Technical Papers					

EXAMINER

✓

DATE CONSIDERED

6/16/03

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.